

Docket Number: 081468-0306725
Client Reference: P-0191.010-US

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

KOSHELEV et al.

Group Art Unit: 2881

Application No.: 09/893,347

Examiner:

Filed: November 5, 2003

Confirmation No.:

For: RADIATION SOURCE, LITHOGRAPHIC APPARATUS, DEVICE MANUFACTURING
METHOD, AND DEVICE MANUFACTURED THEREBY

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

The references were cited by or submitted to the Office in parent application no. 09/893,347, filed June 28, 2001, which is relied upon for an earlier filing date under 35 U.S.C. §120. Thus, copies of these references are not attached. 37 C.F.R. §1.98(d).

Respectfully Submitted,

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Atty. Dkt. No.	M#	Client Ref.
	306725	P-0191.011-US

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant: KOSHELEV et al.	
Appln. No.: TO BE ASSIGNED	
Filing Date: November 5, 2003	
Examiner: NOT ASSIGNED	Group Art Unit:

Date: November 5, 2003 Page 1 of 1

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	4,494,043	01/1985	Stallings et al.			
	BR	4,644,576	02/1987	Kuyel			
	CR	6,414,438	07/2002	Borisov et al.			
	DR						
	ER						
	FR						
	GR						
	HR						
	IR						
	JR						
	KR						
	LR						
	MR						
	NR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
							Enclosed	No	Enclose	No
	OR	0 480 617 A2	10/1991	Europe	Jewell et al.					
	PR									
	QR									
	RR									
	SR									
	TR									
	UR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

	VR	Patent Abstracts of Japan, Publication No. 62176038, August 1, 1987.				
	WR	Bergmann, K., et al., "Highly Repetitive, Extreme-Ultraviolet Radiation Source Based on a Gas-Discharge Plasma," <i>Applied Optics</i> , Vol. 38, No. 25, September 1, 1999, pp. 5413-17.				
	XR	Va'vra, J., et al., "Soft X-Ray Production in Spark Discharges in Hydrogen, Nitrogen, Air, Argon and Xenon Gases," <i>Nuclear Instruments & Methods in Physics Research, Section A</i> , Vol. 418, No. 2-3, December 1998, pp. 405-419.				
	YR	Melnychuk et al., "Plasma Focus Light Source with Improved Pulse Power System," Pub. No: US 2003/0006383 A1, published January 9, 2003				

Examiner Date Considered:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.